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MEMC 99-0900 (2632)
PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Fuerhoff et al.

Art Unit 1765

Serial No. 09/502,340

Filed February 10, 2000

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON
CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

Examiner M. Anderson

January 16, 2002

LETTER TO THE PATENT AND TRADEMARK OFFICE

TO THE COMMISSIONER FOR PATENTS,

SIR:

In response to the Office action mailed September 16, 2002, please consider the following
remarks:

REMARKS

Applicants have thoroughly considered the Examiner's remarks but respectfully disagree and request further reconsideration of the application in light of the following remarks.

Claims 1-10 stand rejected under 35 U.S.C. 103(a) as being unpatentable over Cope, U.S. Patent No. 3,761,692. Claims 7 and 8 also stand rejected under 35 U.S.C. § 103(a) as being unpatentable over the Cope patent, in view of Araki et al. (U.S. Patent No. 5,089,238). The Examiner admits that the Cope reference fails to show every feature of the claimed invention and asserts that the Cope system differs from the present invention only in that PID control is also performed by Cope on the pull rate. To remedy this deficiency, the Examiner notes that "the pull rate adjustment reads on the application's substantially following a set velocity profile because